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Erratum: "Influence of random roughness on cantilever curvature sensitivity" [Appl. Phys. Lett. 96, 041912 (2010)]

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Published in:
Applied Physics Letters

DOI:
[10.1063/1.3442492](https://doi.org/10.1063/1.3442492)

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Document Version
Publisher's PDF, also known as Version of record

Publication date:
2010

[Link to publication in University of Groningen/UMCG research database](#)

Citation for published version (APA):

Ergincan, O., Palasantzas, G., & Kooi, B. J. (2010). Erratum: "Influence of random roughness on cantilever curvature sensitivity" [Appl. Phys. Lett. 96, 041912 (2010)]. *Applied Physics Letters*, 96(22), [229901]. <https://doi.org/10.1063/1.3442492>

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Citation: *Appl. Phys. Lett.* **96**, 229901 (2010); doi: 10.1063/1.3442492

View online: <https://doi.org/10.1063/1.3442492>

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(Received 26 April 2010; accepted 27 April 2010; published online 1 June 2010)

[doi:10.1063/1.3442492]

Due to error Figs. 2 and 3 (and captions) shown in the published paper are not the correct ones. Results, discussion, and conclusions of the paper remain unaltered by this correction.

FIG. 2. Cantilever sensitivity T/T_0 as a function of long wavelength roughness ratio w/ξ for $w=1$ nm, different roughness exponents H , and Poisson ratio $\nu^L=0.18$ [corresponding to Si(111)]. The inset shows the dependence of the average local surface slope on the roughness ratio w/ξ for different roughness exponents H .

FIG. 3. (Color online) Cantilever sensitivity T/T_0 as a function of long wavelength roughness ratio w/ξ for $w=1$ nm, $H=0.5$, and two different Poisson ratios, $\nu^L=0.18$ [corresponding to Si(111)] and $\nu^L=0.28$ [corresponding to Si(100)]. The inset shows a typical gold rough surface deposited onto Si with $H=0.9$, $w=7$ nm, and $\xi=30$ nm yielding $w/\xi=0.23$.

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